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Bib Data Sheet

CONFIRMATION NO. 6404

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|--|---|----------------------------------|---|---|--------------------------------|
| SERIAL NUMBER 09/901,038 | FILING DATE 07/10/2001 RULE | CLASS 438 | GROUP ART UNIT 1765 | ATTORNEY DOCKET NO. 50090-301 | |
| APPLICANTS Toshihiro Yamashita, Tokyo, JAPAN; Hirotoishi Ise, Tokyo, JAPAN; ** CONTINUING DATA ***** <i>42</i> ** FOREIGN APPLICATIONS ***** JAPAN 2000-403083 12/28/2000 <i>42</i> | | | | | |
| IF REQUIRED, FOREIGN FILING LICENSE GRANTED ** 08/23/2001 | | | | | |
| Foreign Priority claimed <input checked="" type="checkbox"/> yes <input type="checkbox"/> no 35 USC 119 (a-d) conditions met <input checked="" type="checkbox"/> yes <input type="checkbox"/> no <input type="checkbox"/> Met after Allowance <i>42</i> Verified and Acknowledged _____ Examiner's Signature _____ Initials _____ | | STATE OR COUNTRY JAPAN | SHEETS DRAWING 3 | TOTAL CLAIMS 18 | INDEPENDENT CLAIMS 2 |
| ADDRESS McDermott, Will & Emery 600 13th Street, N.W. Washington, DC 20005-3096 | | | | | |
| TITLE Plasma processing system in which wafer is retained by electrostatic chuck, plasma processing method and method of manufacturing semiconductor device | | | | | |
| FILING FEE RECEIVED 710 | FEES: Authority has been given in Paper No. _____ to charge/credit DEPOSIT ACCOUNT No. _____ for following: | | <input type="checkbox"/> All Fees <input type="checkbox"/> 1.16 Fees (Filing) <input type="checkbox"/> 1.17 Fees (Processing Ext. of time) <input type="checkbox"/> 1.18 Fees (Issue) <input type="checkbox"/> Other _____ <input type="checkbox"/> Credit | | |

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09-11-06